

Accelerating the Development of High-Speed, mmWave-Frequency Semiconductor Products and Applications

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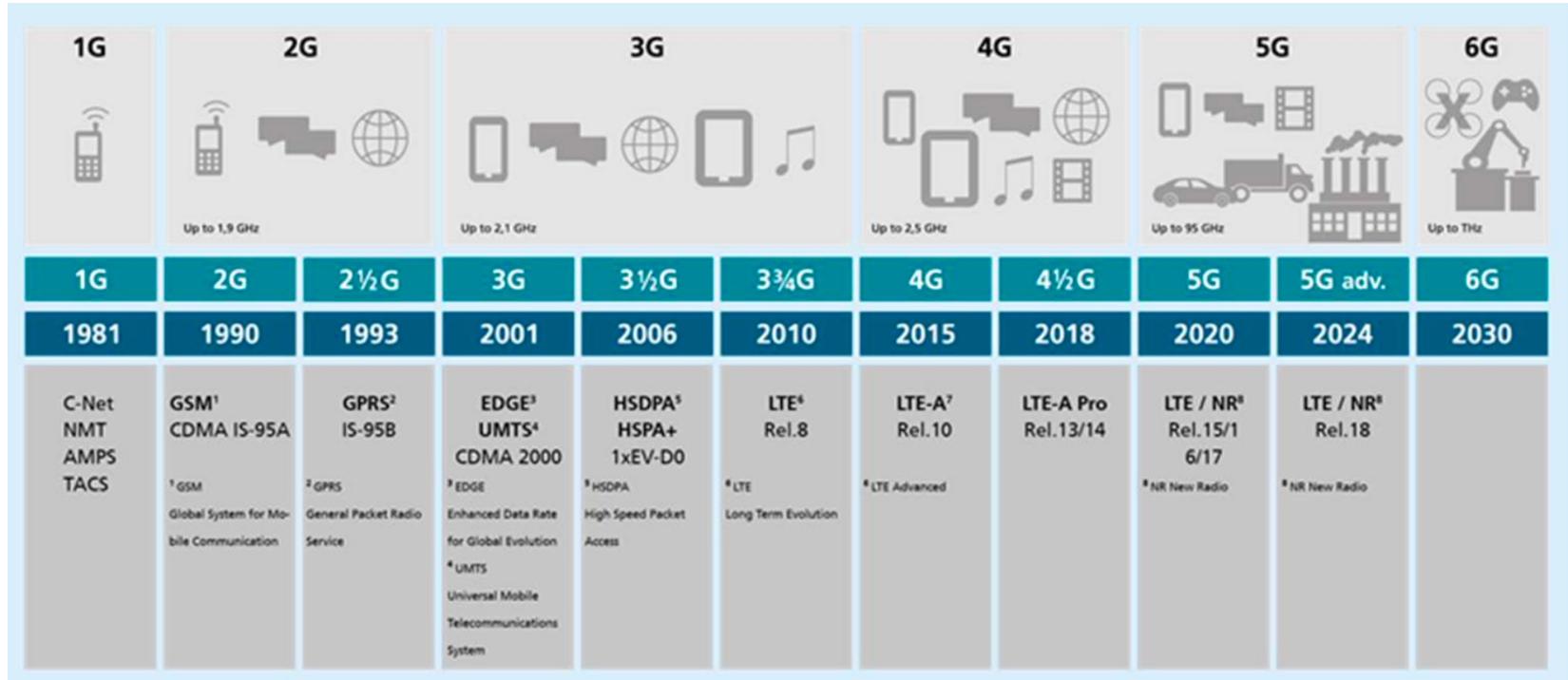


Outline

- Introduction: Instrumentation Evolution
- Modern Systems and Integration
- Automated Test over Multiple Temperatures
- Conclusion

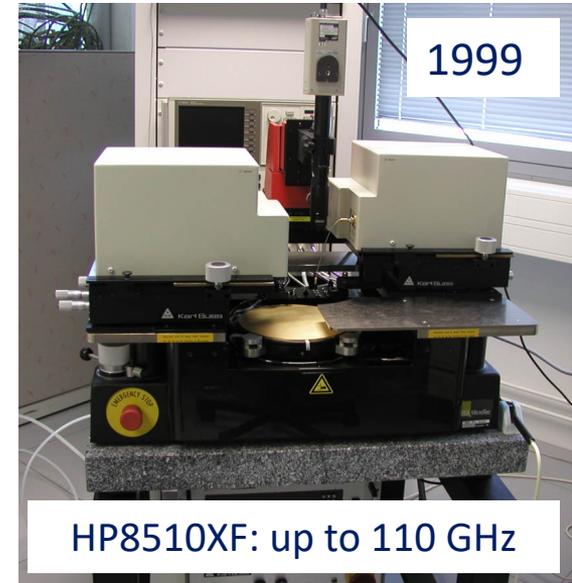


Instrumentation → Communication Enablers



On the Road to 6G: Drivers, Challenges, and Enabling Technologies, *A Fraunhofer 6G white paper*, Fraunhofer, Nov. 2021, 15pp.

1990s: Single-Sweep mmW System



Enabled development of accurate device models for mmW applications

A. Rumiantsev and N. Ridler, "VNA calibration," *IEEE Microwave Mag.*, vol. 9, no. 3, pp. 86-99, 2008, doi: doi:10.1109/MMM.2008.919925.

R. F. Scholz, F. Korndorfer, B. Senapati, and A. Rumiantsev, "Advanced technique for broadband on-wafer RF device characterization," in *ARFTG Microwave Measurements Conference-Spring, 63rd*, 2004, pp. 83-90.

2000s: Broadband Compact System



- Enabled Integration of other instrumentation
 - mmWave Load-Pull
 - RF Noise
- Differential wafer-level mmW measurements became possible
- Boosted development of the Large-signal device models
 - Complex IC development
 - Differential mmW circuits

M. Camp, "RFID - Technologie: Funktion und Einsatz," University of Hannover/Smarter Devices.

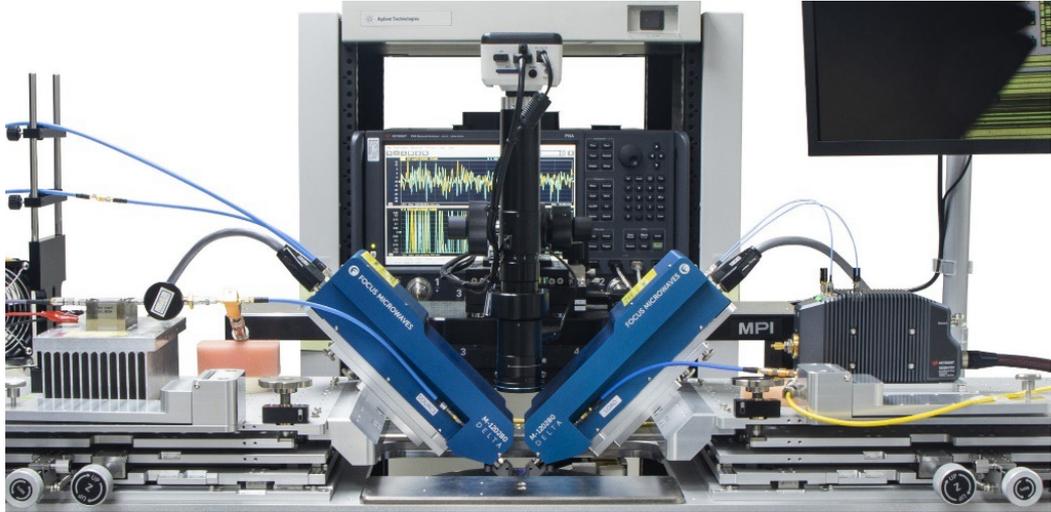
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2017: Size, Performance, Complexity

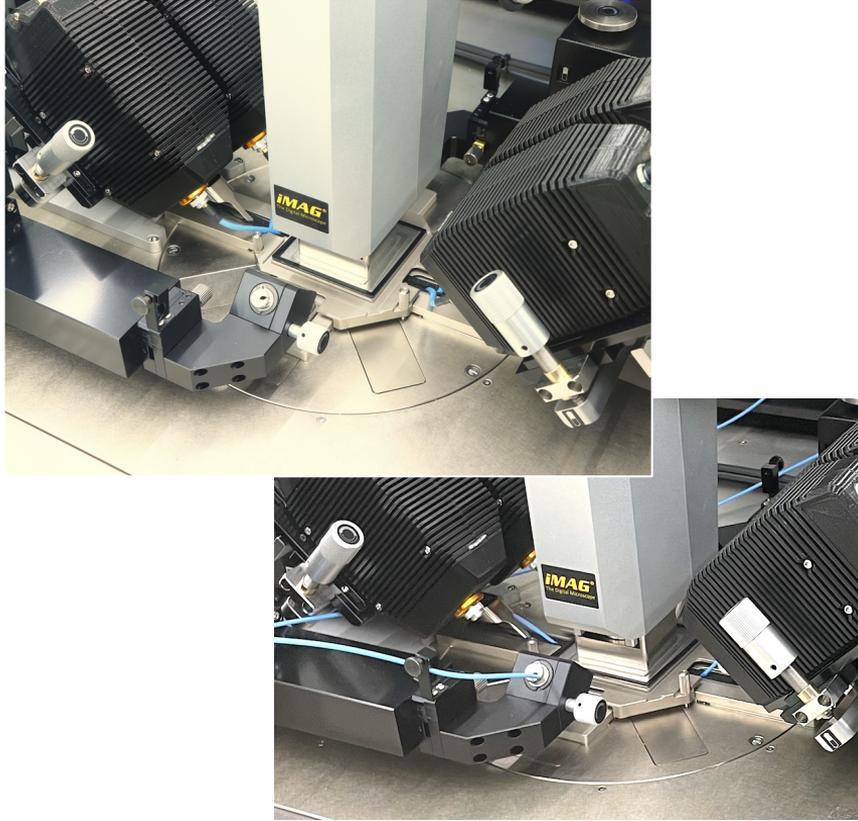


Keysight PNA-X N5291A



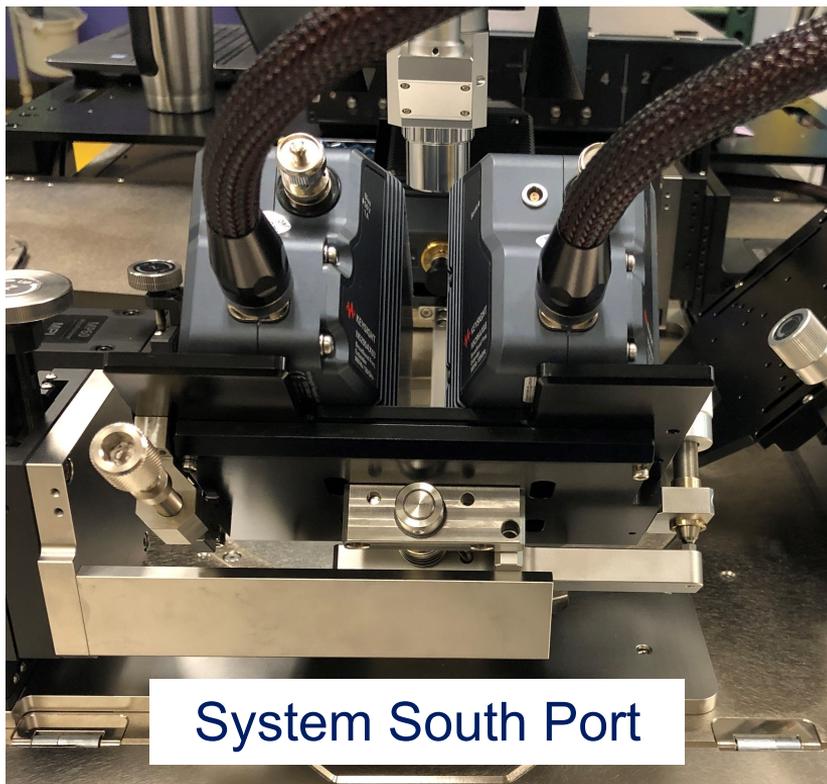
- 900 Hz...120 GHz band, accuracy, dynamic range, speed, calibrated power control, ...
- A “software-defined instrument”: Integration of the elements of Spectrum Analyzers, Noise Figure Analyzers, Signal Generators, Pulse Generators
- Large-signal, Non-linear characterization, time-domain waveforms, modulated waveforms, mmW vectorial Load Pull, ...

Differential PNA-X System Integration on MPI's TS3500-SE System

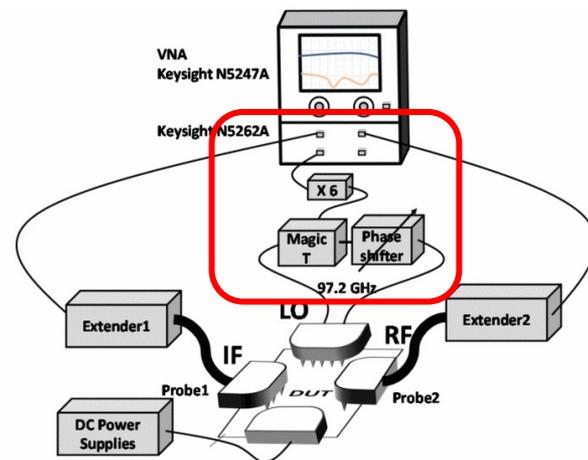


- DUT ShieldEnvironment™ (SE)
- Over-temperature differential mmW IC characterization
 - e.g. automotive IC in the range of -40°C to +175°C
- EMI, light-tight environment
- Easy re-configurable from 67 GHz to the full-sweep DC...120 GHz differential characterization

Integration on the Probe System South Port

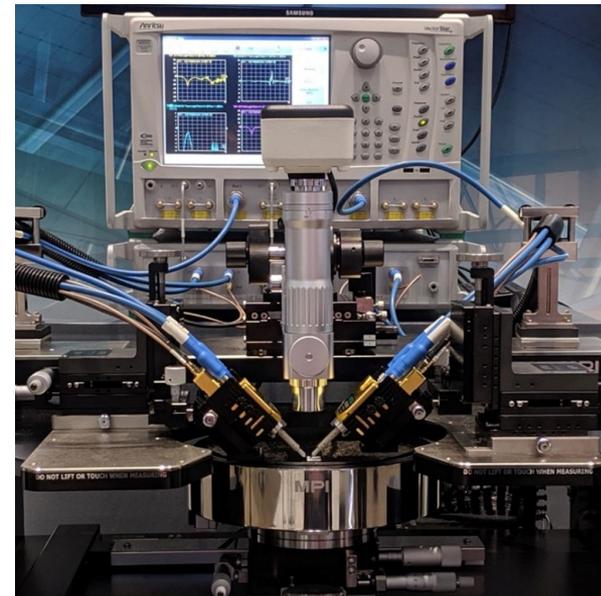
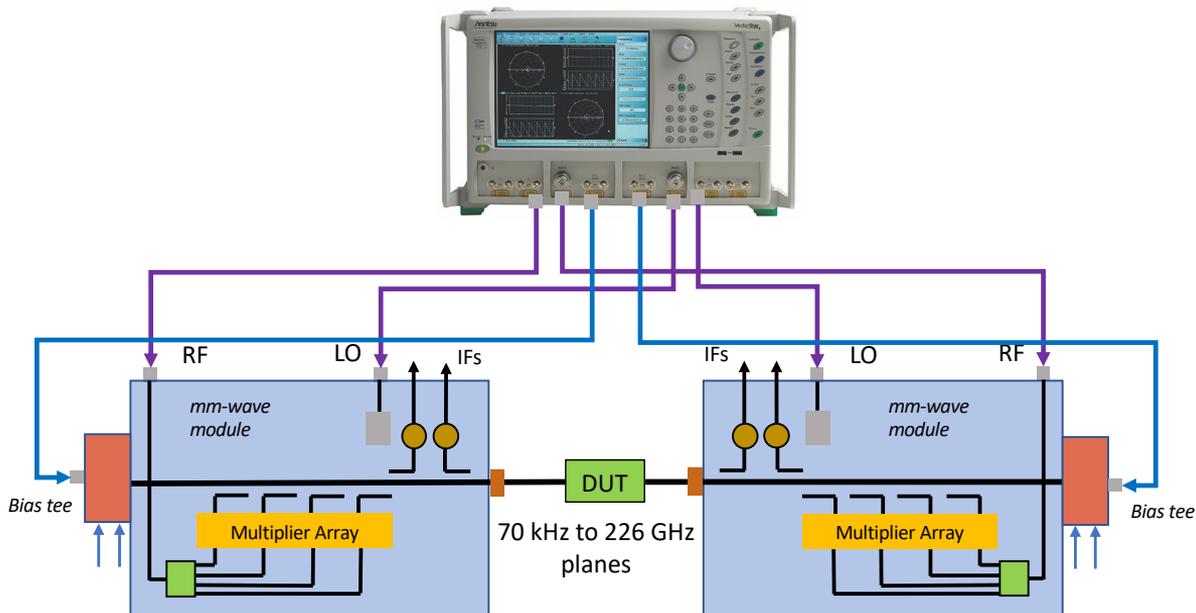


- Enables new-class of characterization
- Magic-T not longer required*



T. Jyo et al., "A DC to 194-GHz Distributed Mixer in 250-nm InP DHBT Technology," 2020 IEEE/MTT-S International Microwave Symposium (IMS), 2020, pp. 771-774.

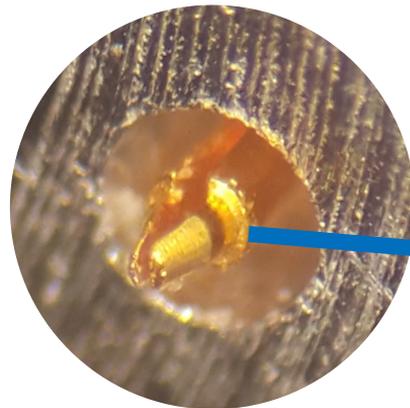
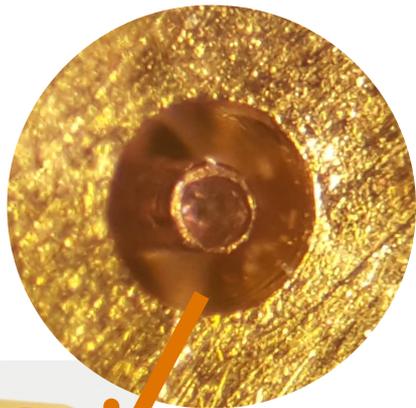
Broadband 70 kHz-220 GHz Single-Sweep VNA



J. Martens and T. Roberts, "Broadband 220 GHz network analysis: structures and performance," 94th ARFTG Microwave Measurement Conference Digest, San Antonio, TX, 26-29 January, 2020.

Probe Interface with 220 GHz Module: MPI's TITAN™ T220A Probe

Slot-less 0.6mm
female center
conductor



Slotted 0.6mm male
pin center conductor

UG-387 Flange



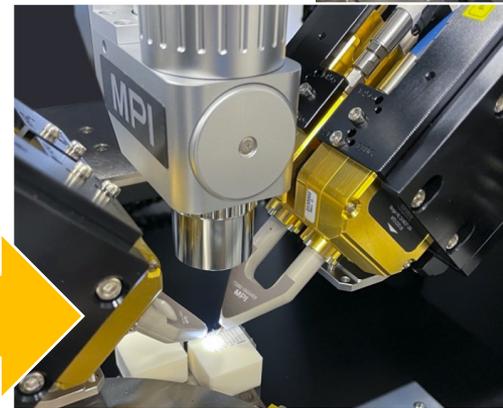
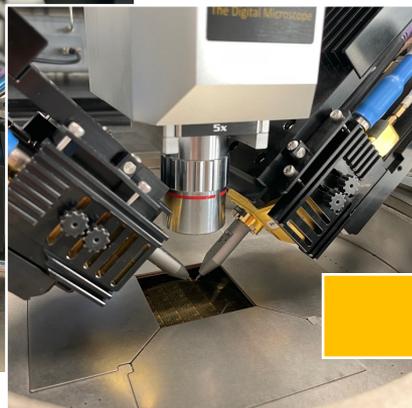
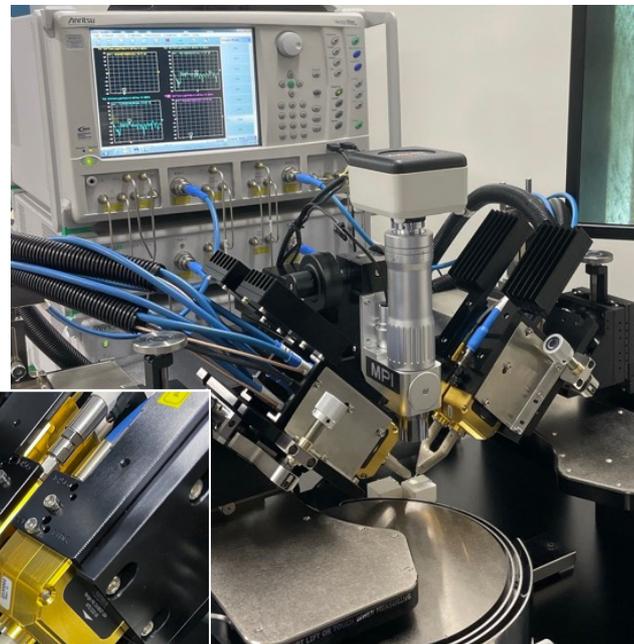
A. Rumiantsev, et al, Calibration, Repeatability and Related Characteristics of On-wafer, Broadband 70 kHz-220 GHz Single-Sweep Measurements, ARFTG-95th

Enabling Differential Broadband Characterization: DC ... 220 GHz

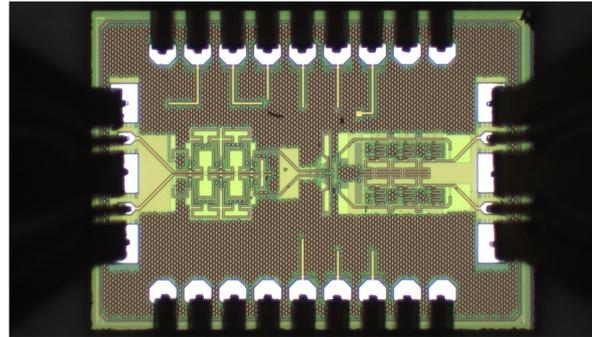
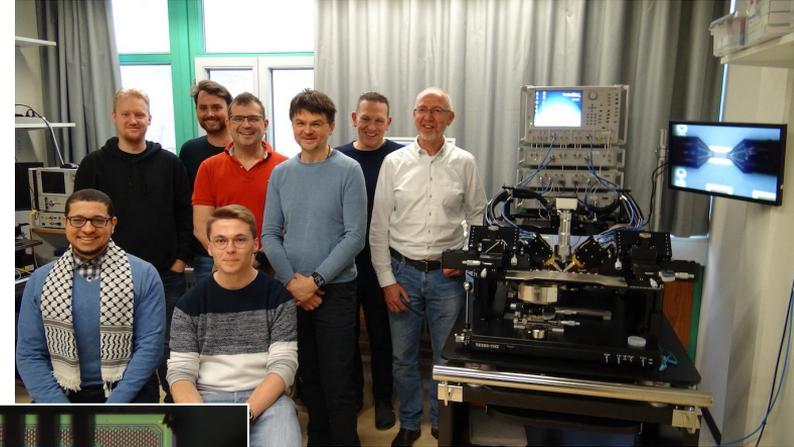
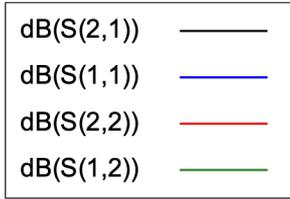
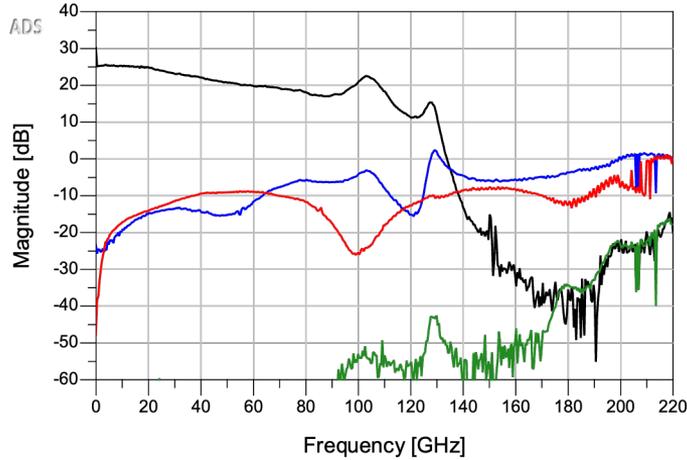


Anritsu ME7838G4
Single Sweep
70 kHz – 220 GHz

MPI's TITAN™ Differential
Probes T220D-GSGSG



Industry-Record Measurements of a Broadband mmWave Driver Circuit



Courtesy: Ulm University, Germany

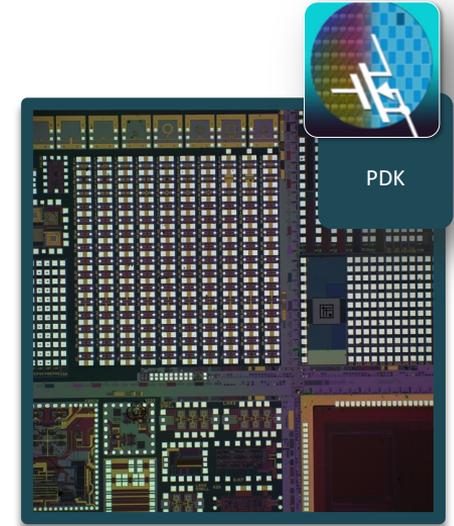
A. Rumiantsev, et al, A Differential Broadband Single-Sweep 70 kHz-220 GHz Wafer-Level System: First Calibration and Measurement Characteristics, ARFTG-100

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Device Characterization for PDK Challenges Increase

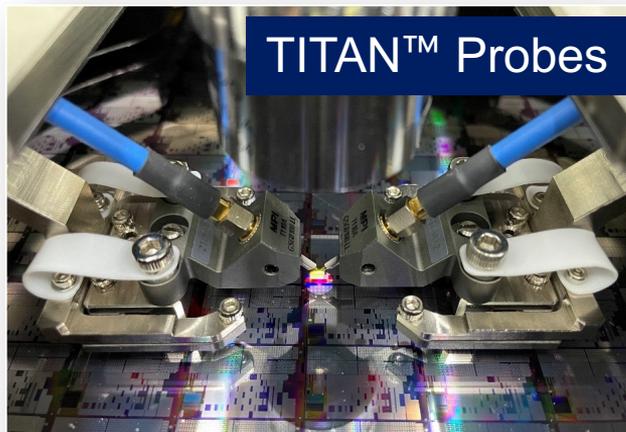
- Wide temperature range:
 - -40, -10, +27, +75, +125, (trend: +175°C)
- “Long-Term Measurements” **LTM**
 - S-parameters sweep for multiple V bias points
 - Different devices and geometries
- Chuck (temperature source) stays in the same location for long time
 - Uneven temperature distribution across the probe platen and the probe arms
 - Thermal stress causes mechanical drift
 - Probes drift and measurement results fail



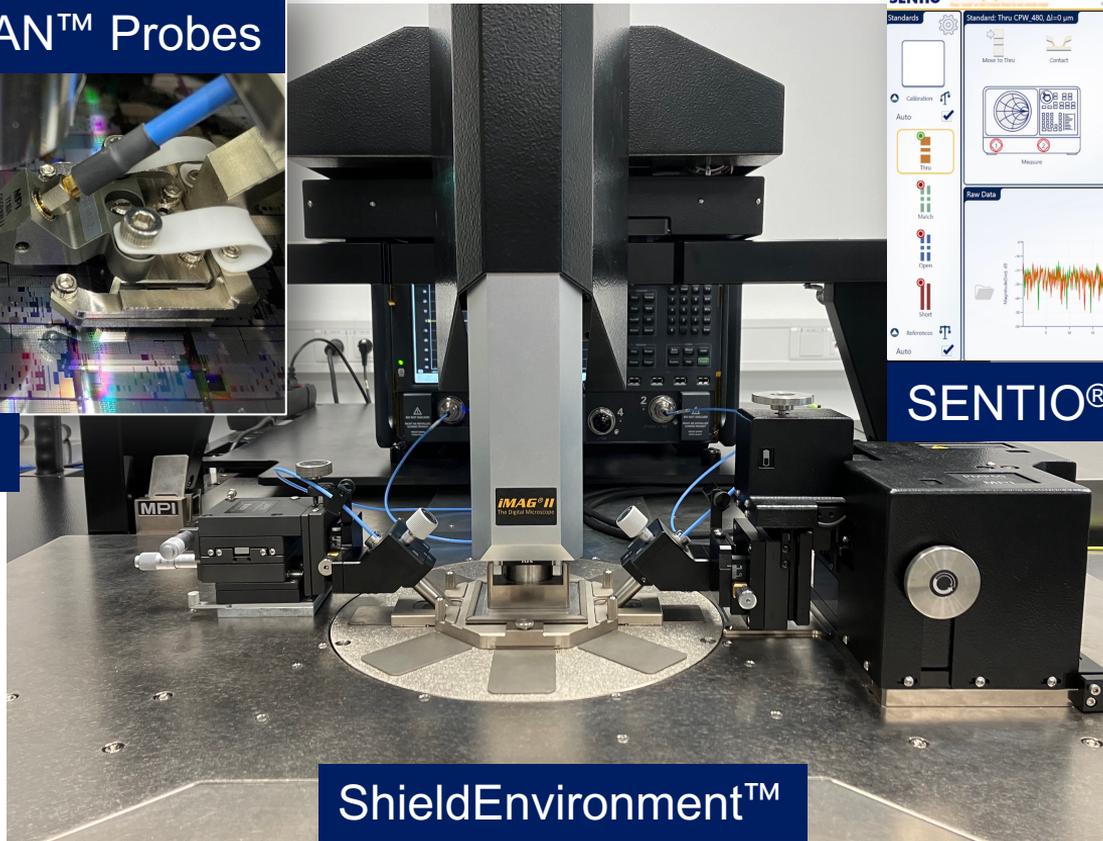
Two Main Problems and MPI's Solution

- How to minimize the mechanical drift?
 - Less to compensate
 - Faster time to data
 - More accurate data
- How to minimize the electrical drift?
 - Reduce time outside of the temperature source
- MPI solutions and vision: ATMT™ Automated Test over Multiple Temperatures
 - Innovative temperature stable hardware
 - Innovative probe adjustment methods with SENTIO® prober software
 - On-wafer calibration with QAlibria® calibration software

MPI's ATMT™ Automated Test over Multiple Temperatures



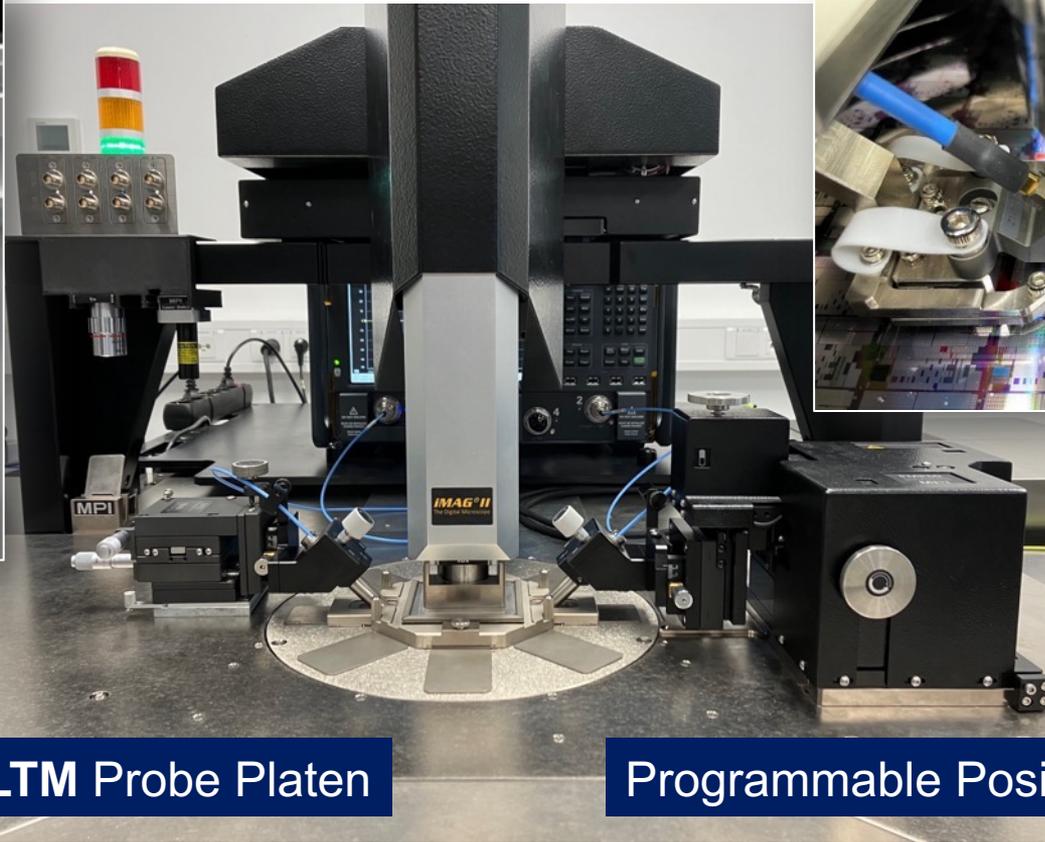
SmartCarrier™



SENTIO® and QAlibria®

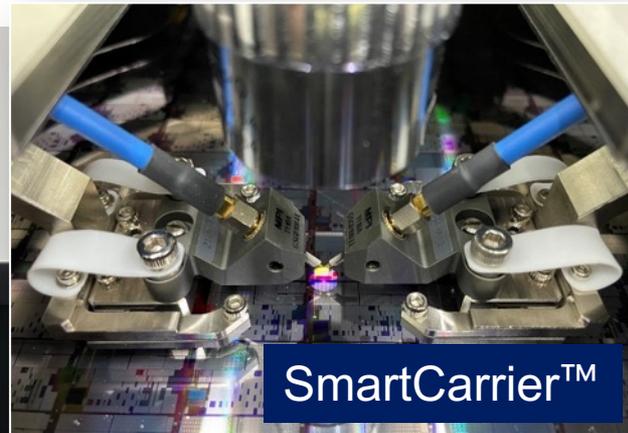
Hardware System Configuration: Example for Two-Port RF

LTM Probe Arm



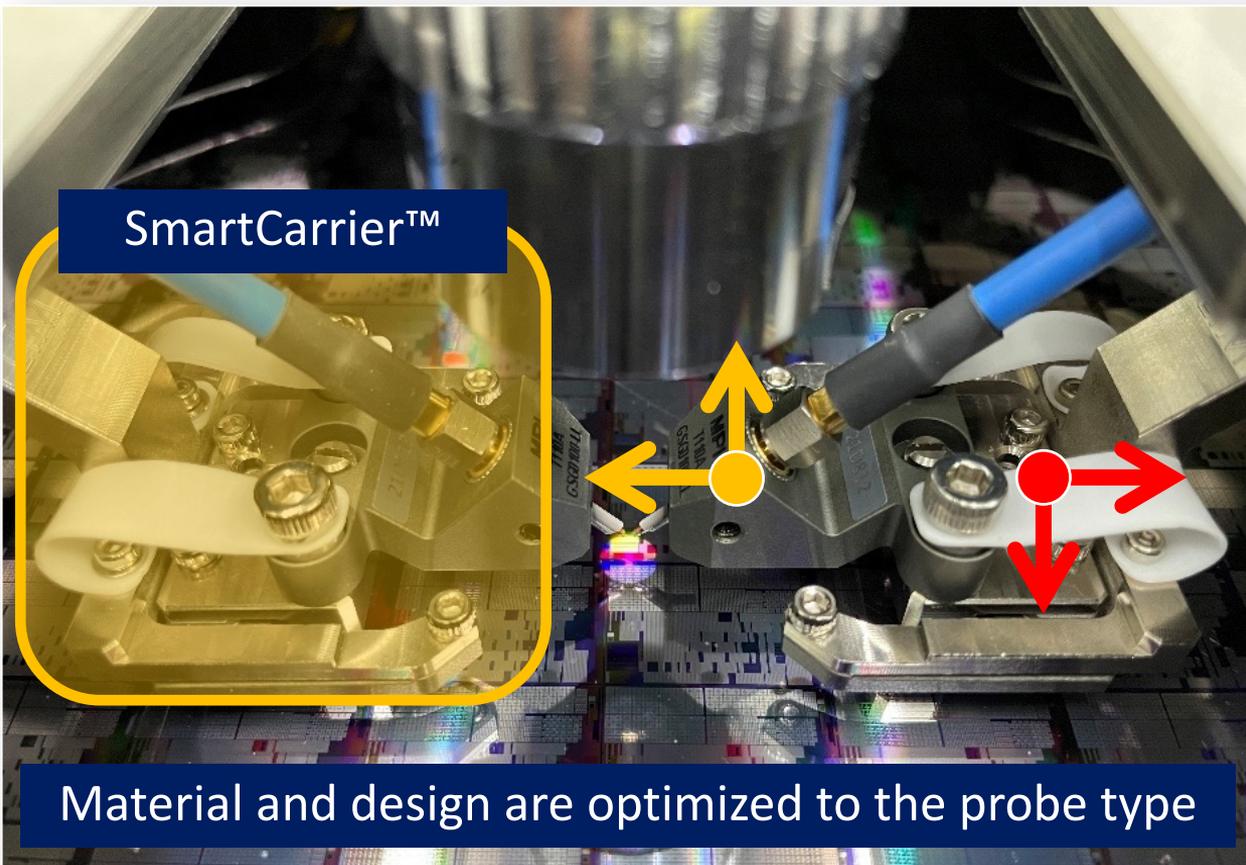
LTM Probe Platen

Programmable Positioner PMP



SmartCarrier™

SmartCarrier™ Compensates Probe Drift in X, Y, and Z



Broadband Single-Sweep over Temperature Characterization

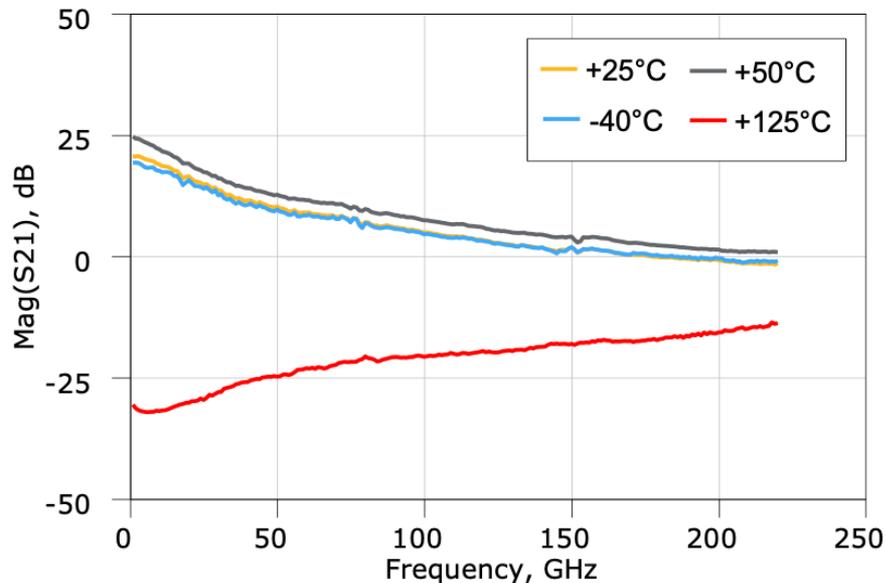
MPI CORPORATION READY FOR THE TEST™

Groundbreaking Achievements in Over-Temperature mmW Broadband Characterization of Semiconductor Devices

As semiconductor technology continues to push boundaries, the demand for accurate and reliable over-temperature characterization techniques becomes paramount. In this technical paper, we delve into the challenges of over-temperature characterization and present innovative solutions that address these challenges. Leveraging the capabilities of Anritsu VectorStar ME7838G 70 kHz-220 GHz broadband VNA, we have developed cutting-edge hardware and software solutions for on-wafer broadband characterization [1]. This paper showcases our industry-first 220 GHz 111AIV™ probe and it highlights the capabilities of SENSIO™ and QILIBRI® probe control and calibration software, respectively. The integrated solution enabled automated on-wafer system calibration with NIST multiline TRL and MPI's TMRR calibration and precise broadband device characterization over a wide range of temperatures. Through detailed examples of InP HBT device under test (DUT) characteristics, we demonstrate the effectiveness and reliability of our solutions.



Fig. 1. Anritsu VectorStar ME7838G 70 kHz-220 GHz broadband VNA integrated with the MPA TS3500-SE system.



DUT characteristics at -40C, +25C, +50C and +125C corrected by on-wafer mTRL

APPLICATION NOTE - QMS-CAS-209-01_07-2023 © MPI Corporation 2023 - Data subject to change without further notice.

1

Refer to: <https://www.mpi-corporation.com/ast/technical-library/>

Conclusion

- Progress in instrumentation enabled the development of the next-generation highly-integrated circuits and system
- Innovative integration solutions for wafer-level characterization without compromising the instrument performance
- Software and system automation solutions for the over-temperature characterization accelerated time-to-data for the next-generation products for 5G and 6G Application Research



Thank You.

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